

ME597/PHYS57000
Fall Semester 2009
Lecture 06

The Transition from STM to AFM

Suggested Reading: G. Binnig, C. Quate and Ch. Gerber, "Atomic Force Microscope", Phys. Rev. Lett. **56**, 930 (1986). *

*cited ~2,000 times

Many materials of interest do not conduct electricity. Is it possible to use scanning probe to study them?

Even at the First International STM Conference in July 1986, there was discussion about how to extend STM techniques to non-conducting materials.

Overcoming Limitation of a Conducting Substrate: the Atomic Force Microscope

VOLUME 56, NUMBER 9

PHYSICAL REVIEW LETTERS

3 MARCH 1986

Atomic Force Microscope

G. Binnig^(a) and C. F. Quate^(b)

Edward L. Ginzton Laboratory, Stanford University, Stanford, California 94305

and

Ch. Gerber^(c)

IBM San Jose Research Laboratory, San Jose, California 95193

(Received 5 December 1985)

Control the
tip-substrate
force!

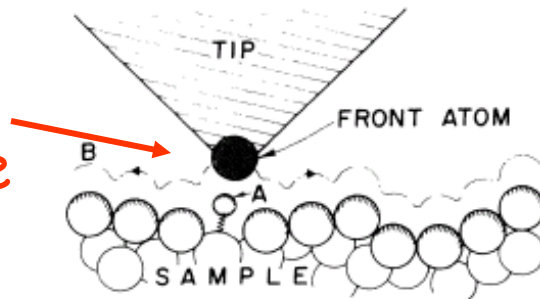


FIG. 1. Description of the principle operation of an STM as well as that of an AFM. The tip follows contour *B*, in one case to keep the tunneling current constant (STM) and in the other to maintain constant force between tip and sample (AFM, sample, and tip either insulating or conducting). The STM itself may probe forces when a periodic force on the adatom *A* varies its position in the gap and modulates the tunneling current in the STM. The force can come from an ac voltage on the tip, or from an externally applied magnetic field for adatoms with a magnetic moment.

Key Idea: use sensitivity of STM to measure the rise and fall of a tip mounted on a cantilever when rastered across an insulating substrate.

Initial Implementation:

First Topographic Scans

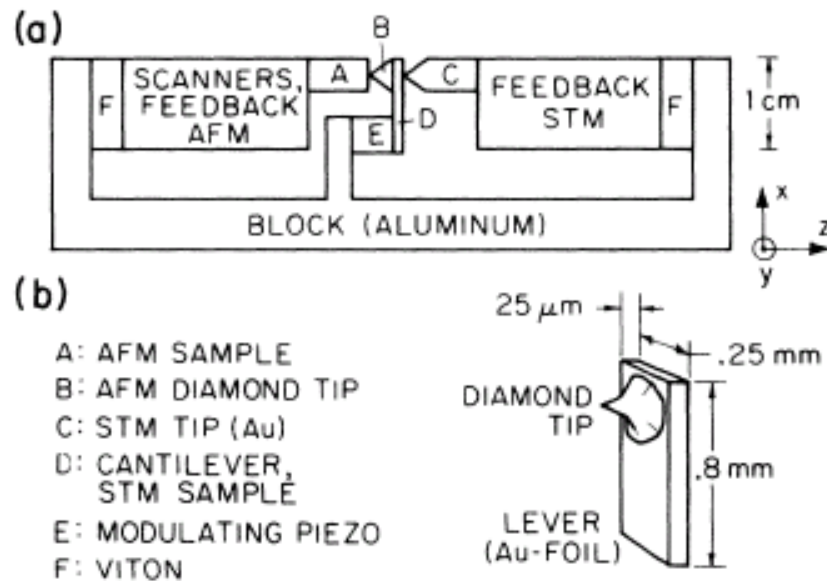


FIG. 2. Experimental setup. The lever is not to scale in (a). Its dimensions are given in (b). The STM and AFM piezoelectric drives are facing each other, sandwiching the diamond tip that is glued to the lever.

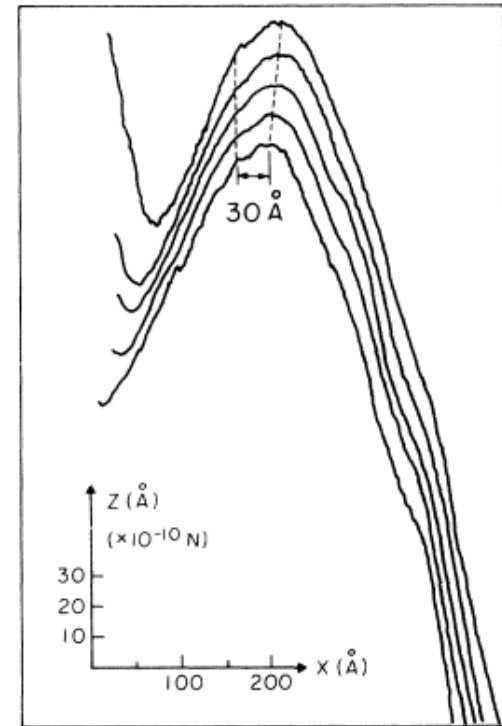
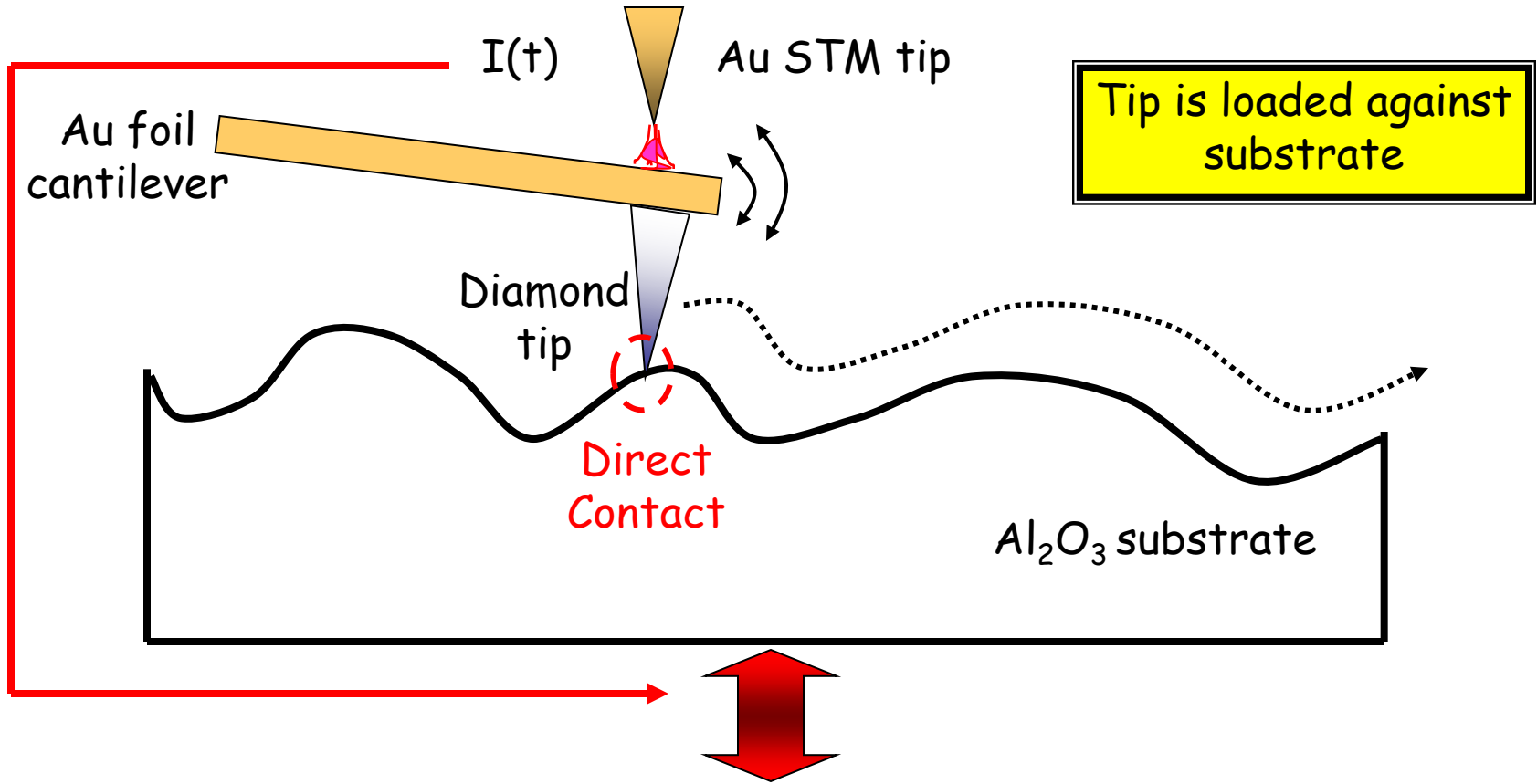
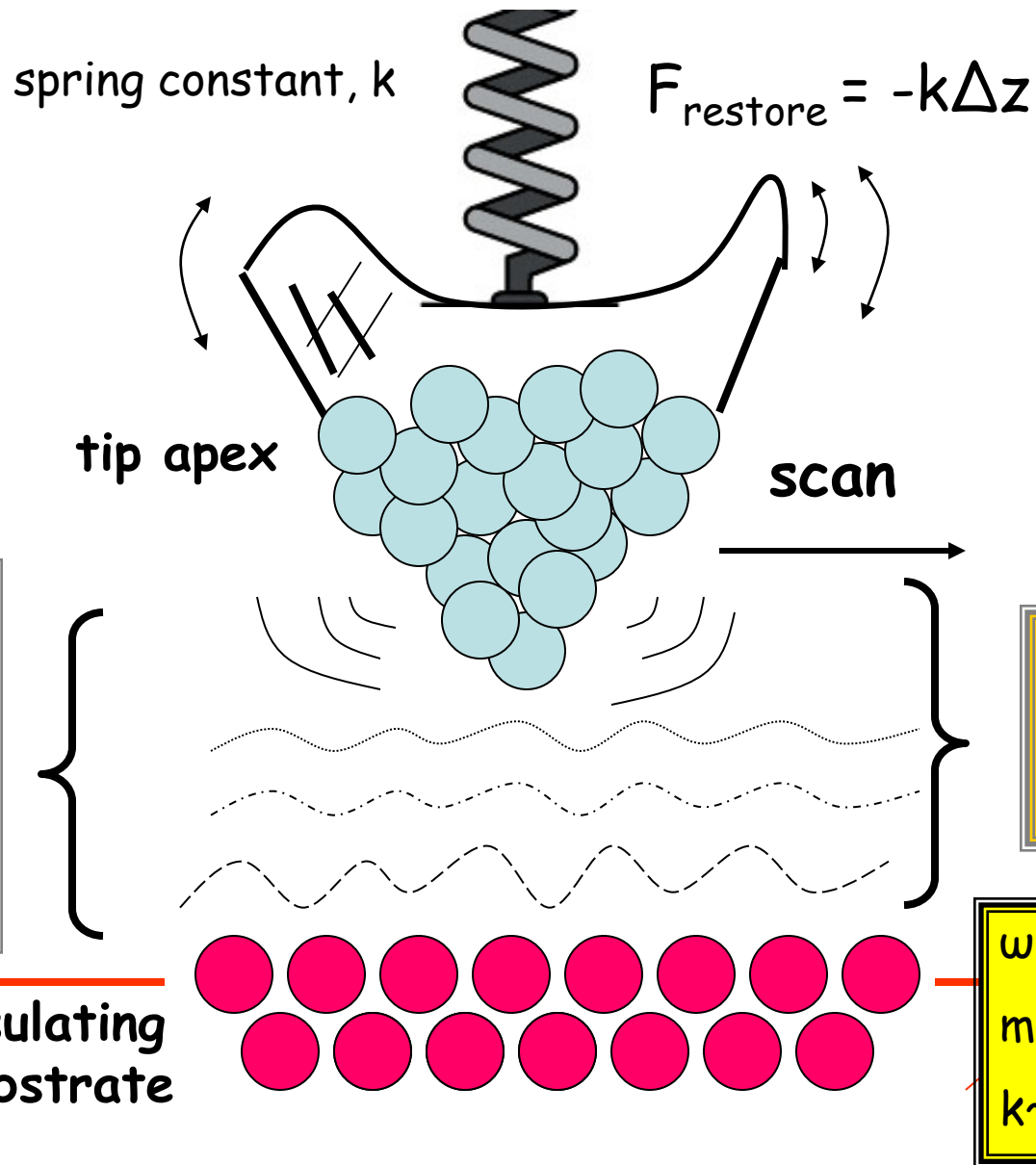


FIG. 3. The AFM traces on a ceramic (Al_2O_3) sample. The vertical scale translates to a force between sample and tip of 10^{-10} N/\AA . For the lower trace the force is near $3 \times 10^{-8} \text{ N}$. The stability of the regulated force is better than 10^{-10} N . The successive traces are displaced by a small drift along the y axis.

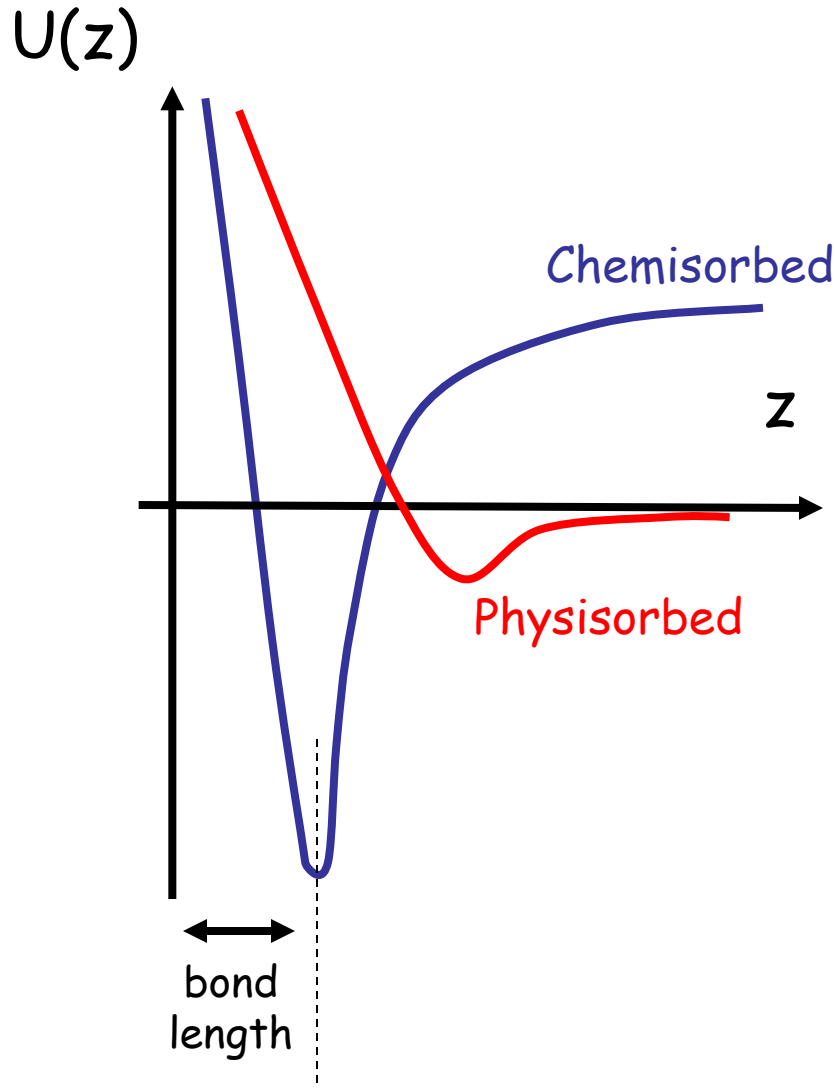
Scanning Mode



What controls the atomic force?

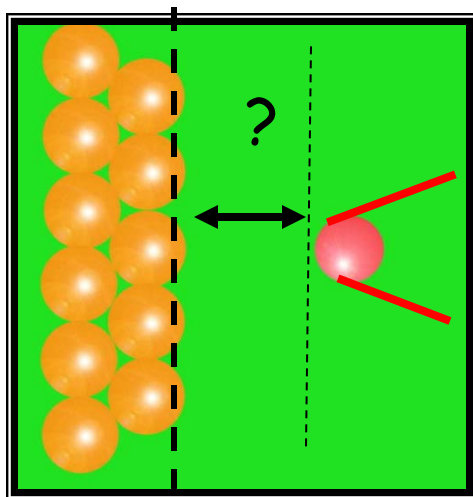


Short-range atom-atom interactions?



	Physisorbed	Chemisorbed
Interaction	vdW bond	chemical bonds (common electronic orbitals)
Energetics	< 20 kJ/mol	>100 kJ/mol
Equilibrium Separation	0.4-0.6 nm (long range)	<0.3 nm (short range)
Adsorbed Layers	>1	1
Specificity	Non specific	Specific
Temperature	depends on boiling point	activation energy

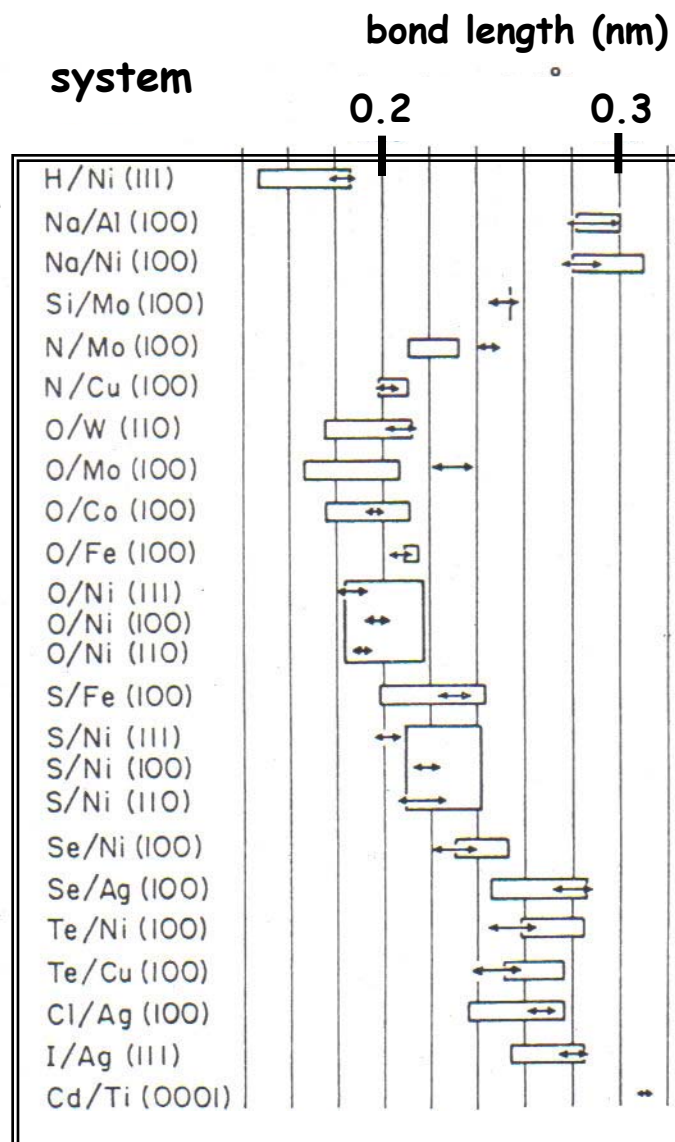
How Close is the Front Atom to the Substrate?



Legend:

↔ bond length for surface structures

▭ bond lengths in bulk and in molecules



Tip-Substrate Interactions

Electrostatic, magnetic

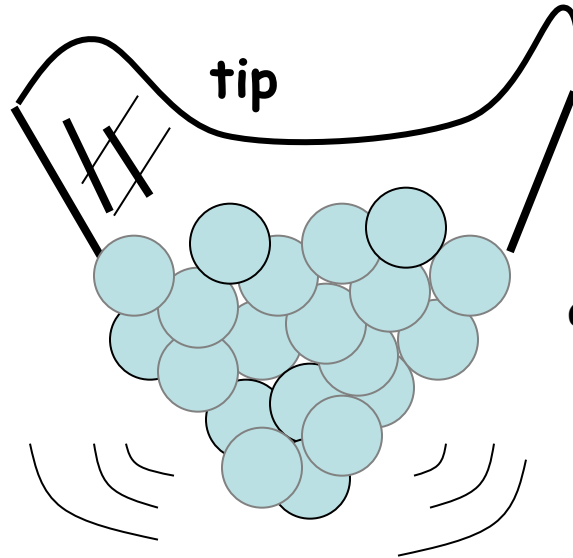
van der Waals (1873)

Capillary

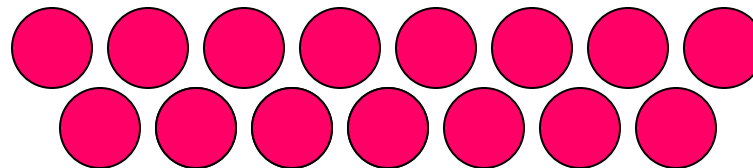
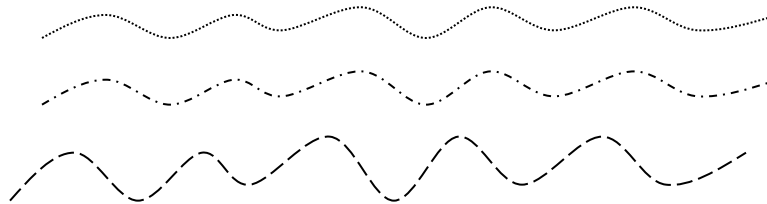
Chemical:
(chemisorbed, physisorbed)

Friction

Deformation (indentation)

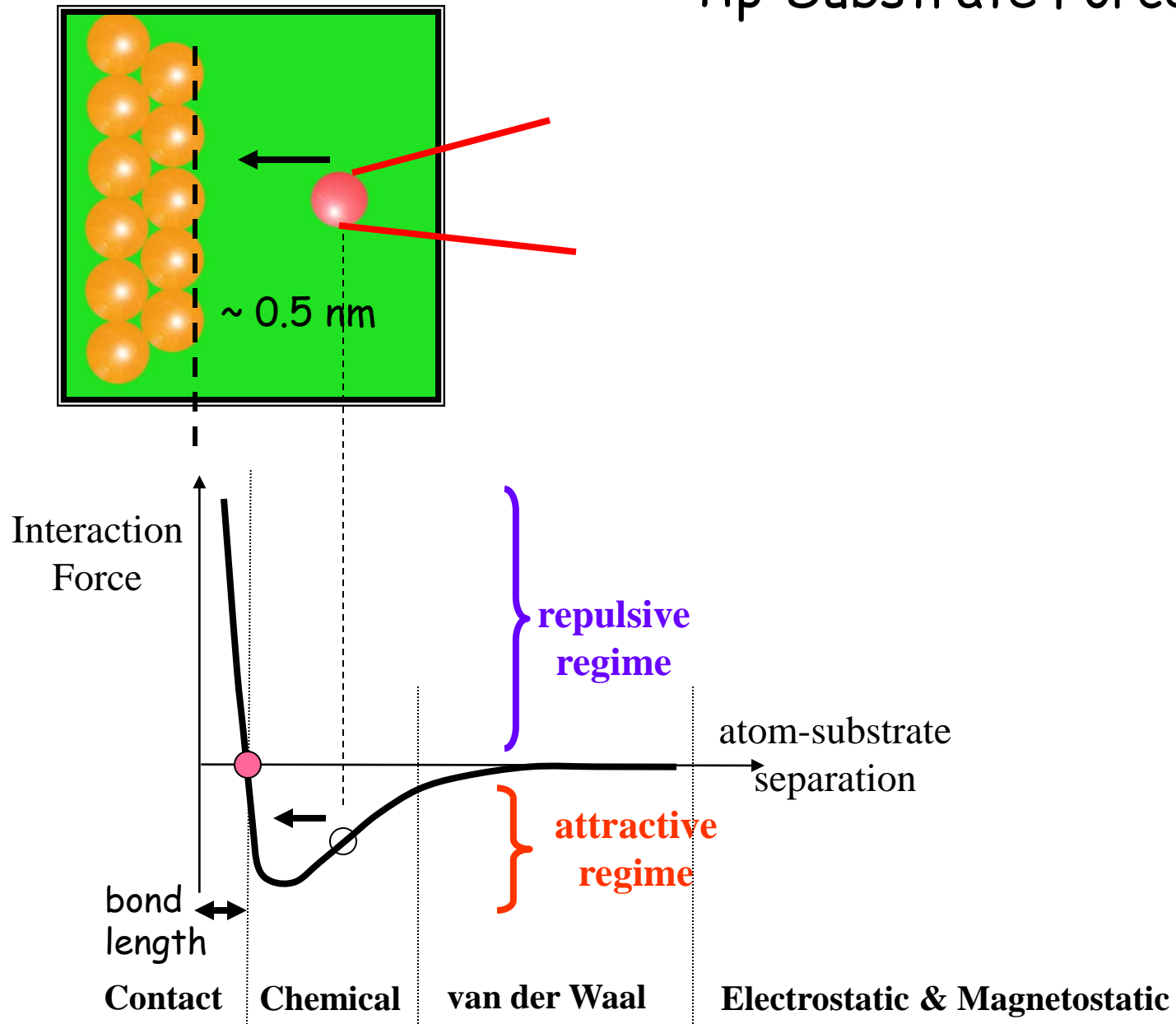


both tip-substrate and atom-atom interactions are important

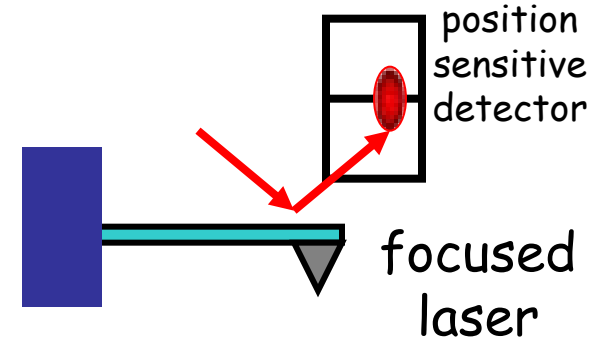
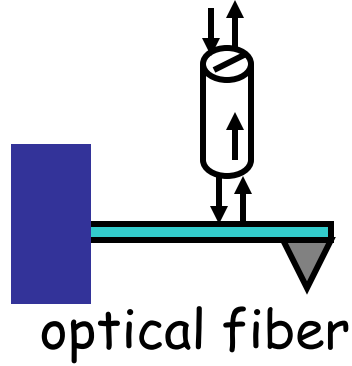
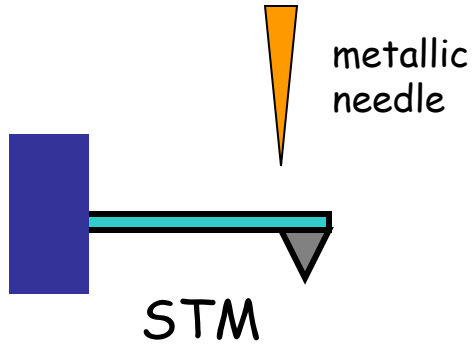


substrate

Tip-Substrate Forces



Detecting Deflection

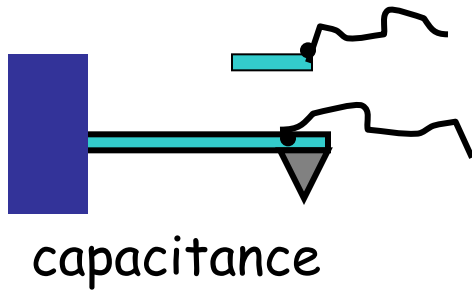


Binnig *et al.*, *Phys. Rev. Lett.* **56** (1986)

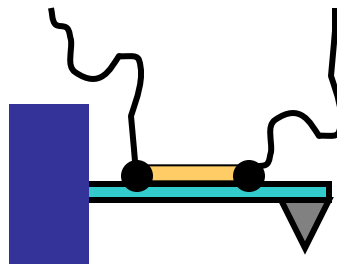
Martin *et al.*, *J. App. Phys.* **95** (1987)

Marti *et al.*, *J. Microscopy*, **152** (1986)

G. Meyer and N. Amer, *Appl. Phys. Lett.* **53** (1988)



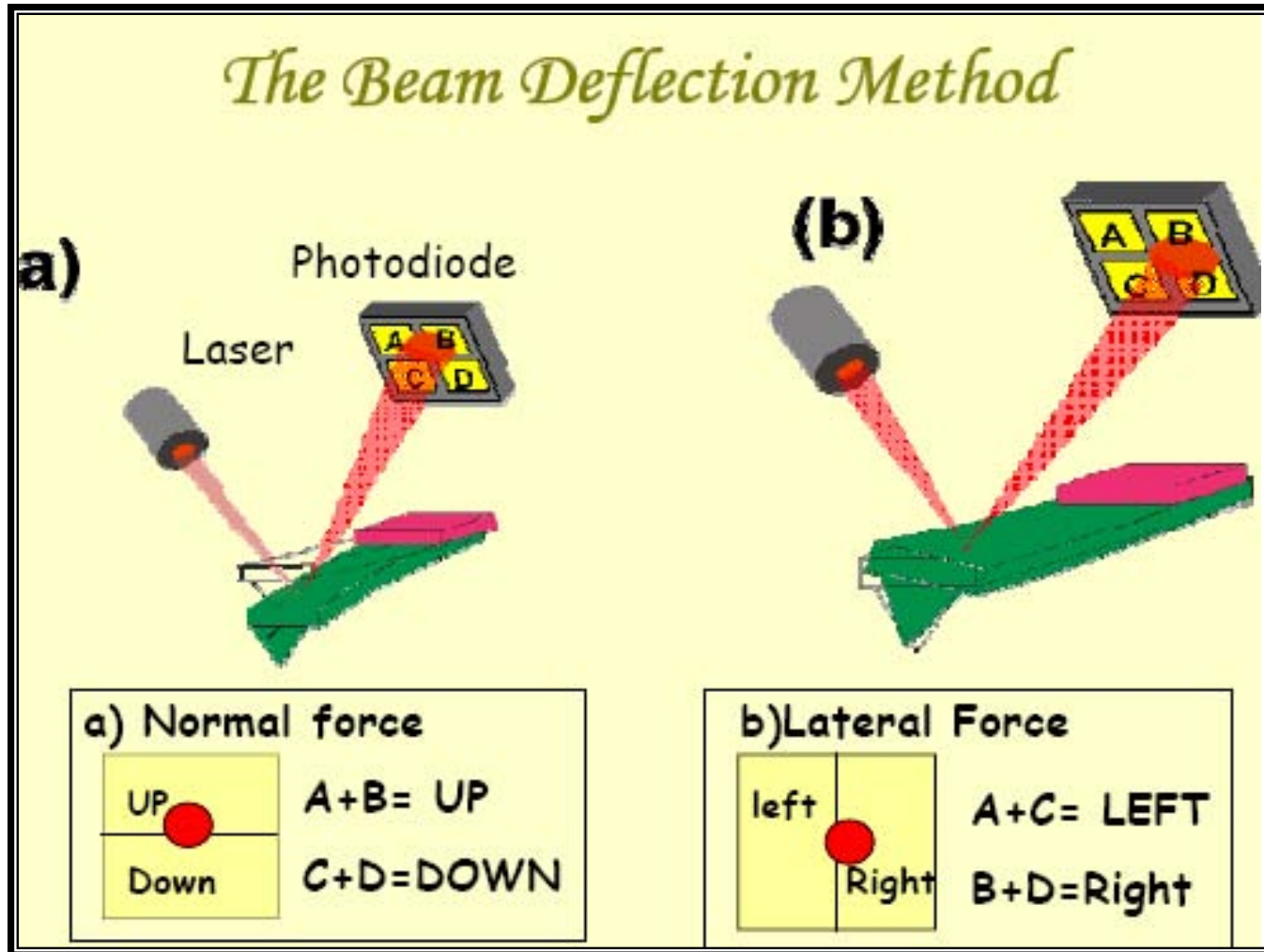
Göddenhenrich *et al.*, *J. Vac. Sci. Technol.* **A8** (1990)



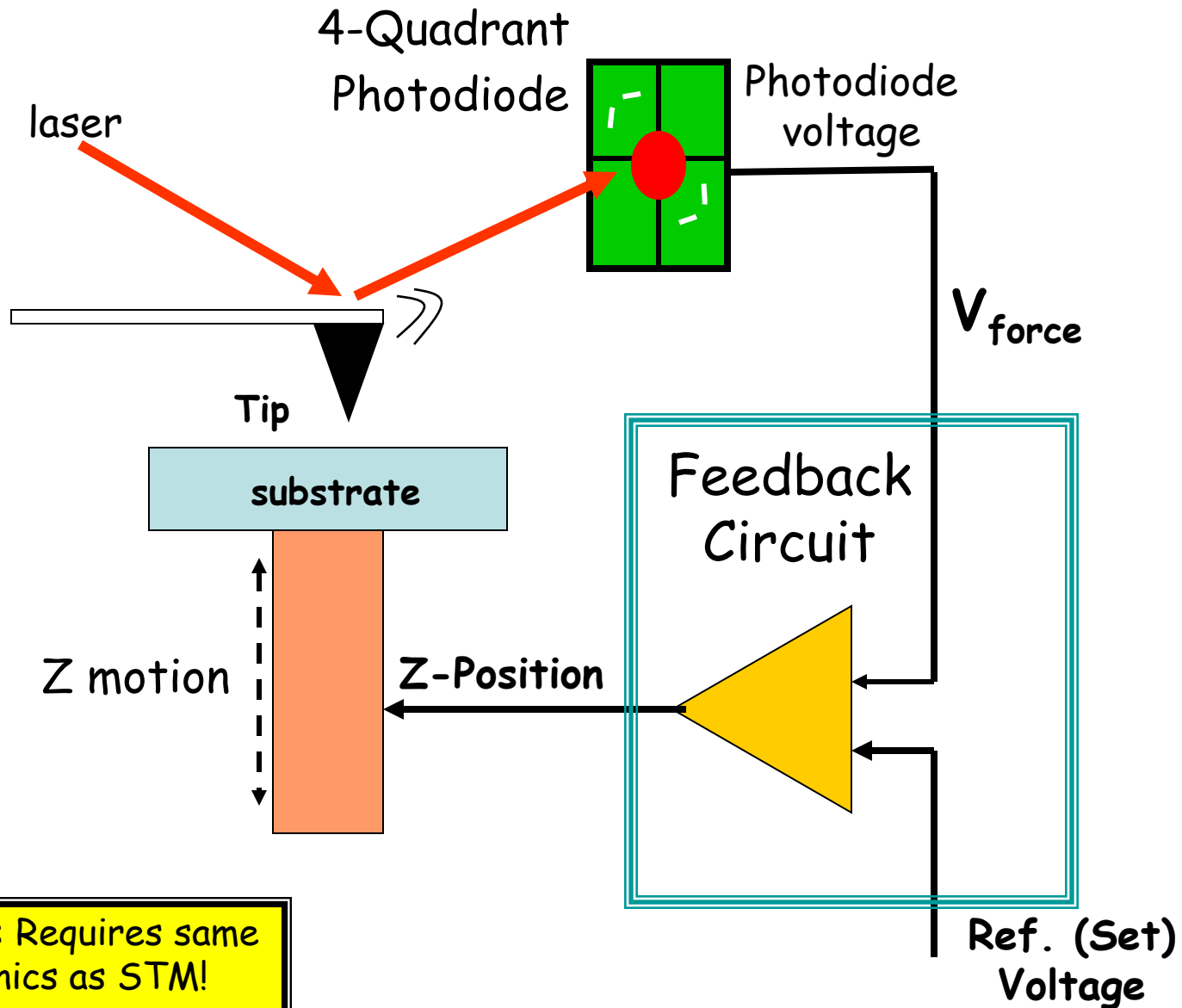
Tortonese *et al.*, *App. Phys. Lett.* **62** (1993)

piezoresistance

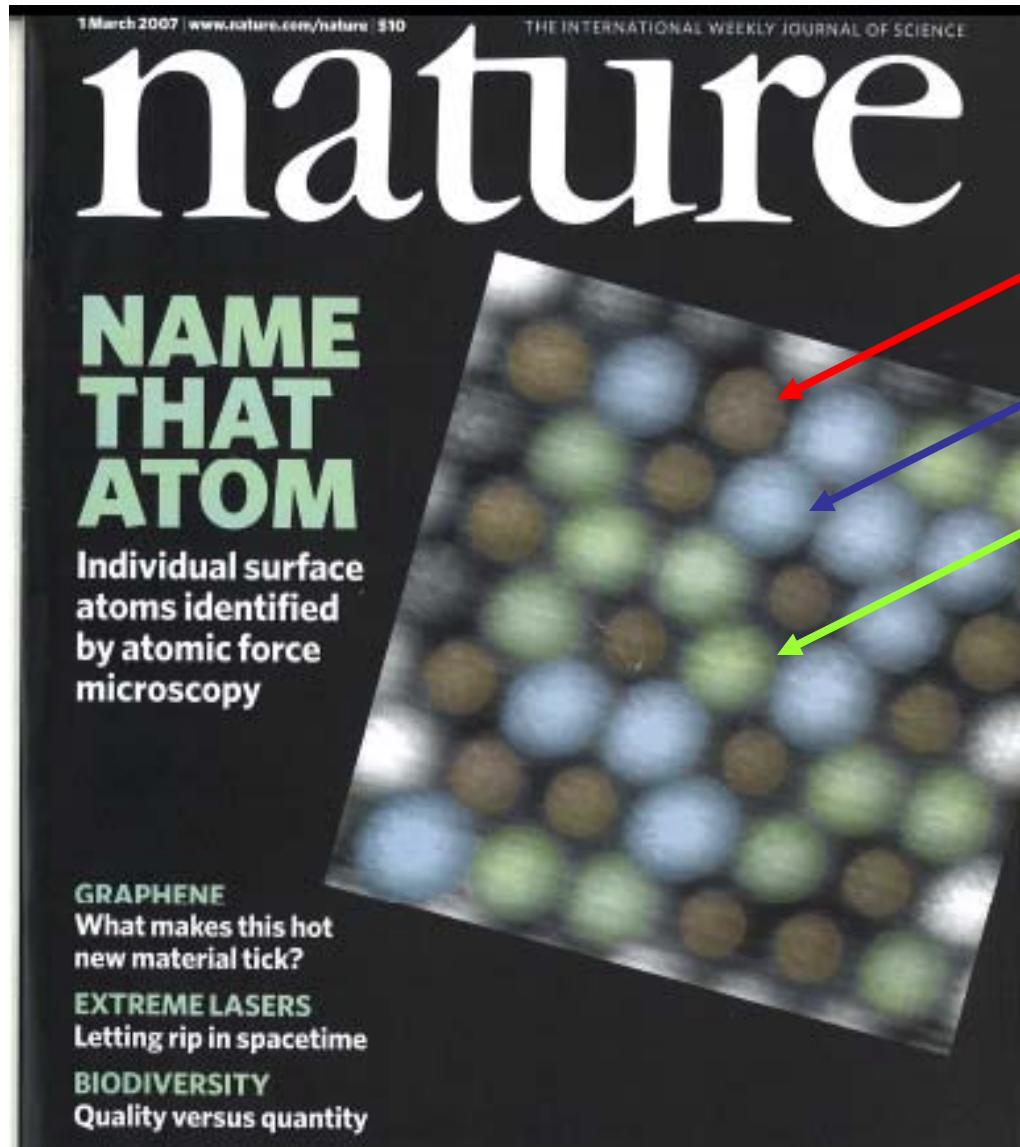
The Method of Choice - Today



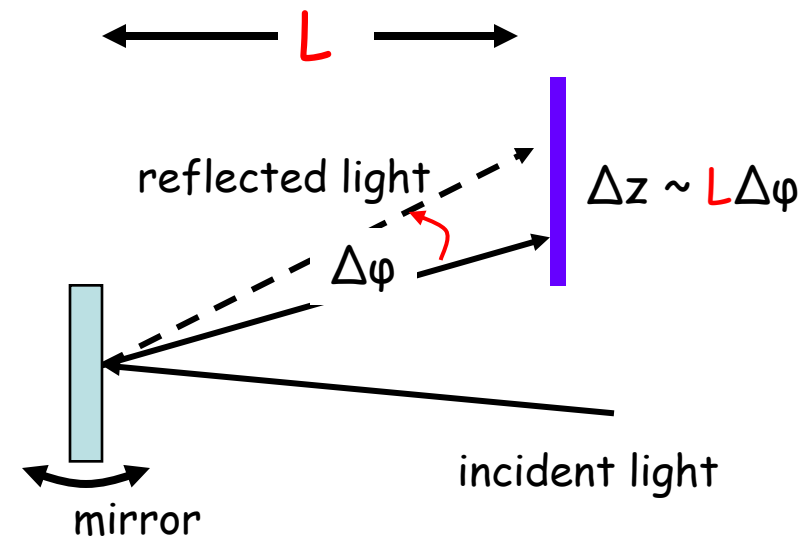
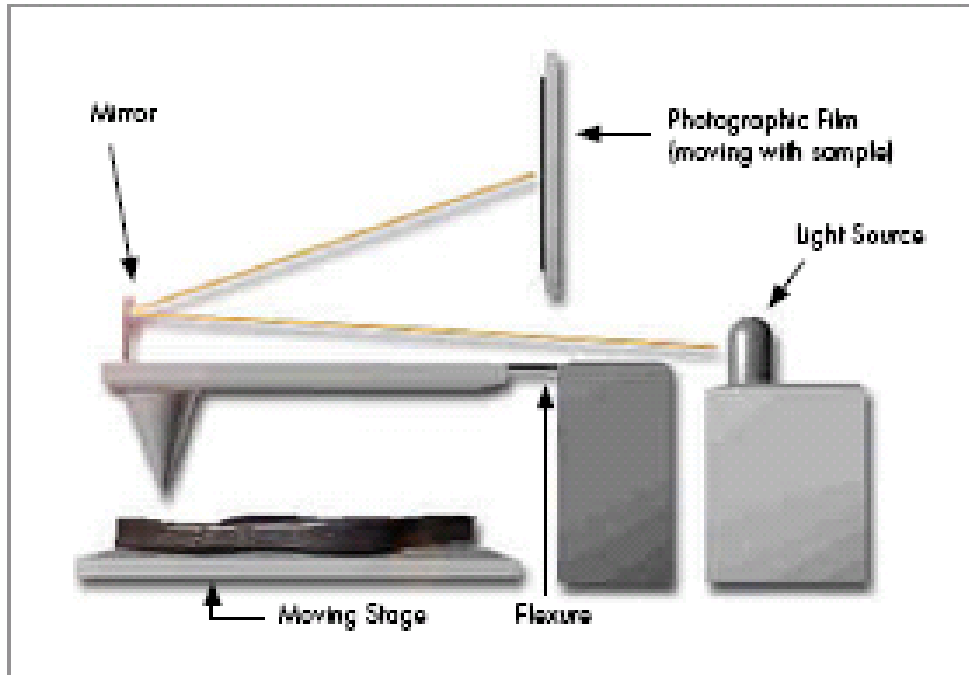
Maintaining a constant force



AFMs have come a long way



Early Stylus Profiler - Schmalz in 1929



The probe is in contact with the substrate

Stylus arm monitors up and down motion of sharp probe mounted at the end of a cantilever

Record motion of the stylus on photographic paper to obtain profile of surface

This "microscope" can generate profile "images" with a magnification of greater than 1000x

Seeing with Proximal Probes - a Selected Timeline for Scanning Probe Microscopy

- 1981 - Binnig and Rohrer invent the first scanning probe microscope - the Scanning Tunneling Microscope (STM)
- 1986 - Binnig, Quate and Gerber invent the Atomic Force Microscope (AFM) - contact mode
- 1987 - non-contact scanning mode introduced
- 1988 - implementation of computer control
- 1989 - optical beam bounce introduced
- 1991 - microfabricated tips
- 1993 - intermittent contact mode introduced

A Checklist of Various Scanning Probe Techniques; SxM

Table adapted from *Nanotechnology: Towards a Molecular Construction Kit*, edited by A. ten Wolde (1998)

Scanning Tunneling Microscopy (STM)

STM Techniques:

- UHV STM - Ultra-high vacuum STM
- STS - Scanning Tunneling Spectroscopy
- CITS - Current Imaging Tunneling Microscopy
- BEEM – Ballistic Electron Emission Spectroscopy
- Tunneling Acoustic Microscopy
- AC-STM - Alternating Current Scanning Tunneling Microscopy

Atomic Force Microscopy (AFM)/Scanning Force Microscopy (SFM)

Contact-mode AFM Techniques:

- FFM - Friction Force Microscopy
- SFFM - Scanning Friction Force Microscopy
- SHFM - Shear-Force Microscopy
- FMM - Force Modulation Microscopy
- AFAM - Atomic Force Acoustic Microscopy
- SLAM - Scanning Local-Acceleration Microscopy
- CAFM – Conductance Atomic Force Microscopy

Dynamic Force Microscopy (DFM)

AM DFM - Amplitude Modulation DFM

FM DFM - Frequency Modulation DFM

DFM Techniques:

- CFM - Chemical Force Microscopy
- EFM - Electrostatic Force Microscopy
- KFM - Kelvin Force Microscopy
- MFM - Magnetic Force Microscopy
- MRFM - Magnetic Resonance Force Microscopy
- SMM - Scanning Maxwell-Stress Microscopy
- SNAM - Scanning Near-Field Acoustic Microscopy

Scanning Near-Field Optical Microscopy (SNOM)/Near Field Scanning Optical Microscopy (NSOM)

SNOM/NSOM Techniques:

- PSTM - Photon Scanning Tunneling Microscopy
- SIAM - Scanning Interferometric Apertureless Microscopy
- SPNM - Scanning Plasmon Near-Field Microscope

Scanning Thermal Microscopy (SThM)

SOAM - Scanning Optical Absorption Microscopy

SCPM - Scanning Chemical-Potential Microscopy

Scanning Capacitance Microscopy (SCAM)

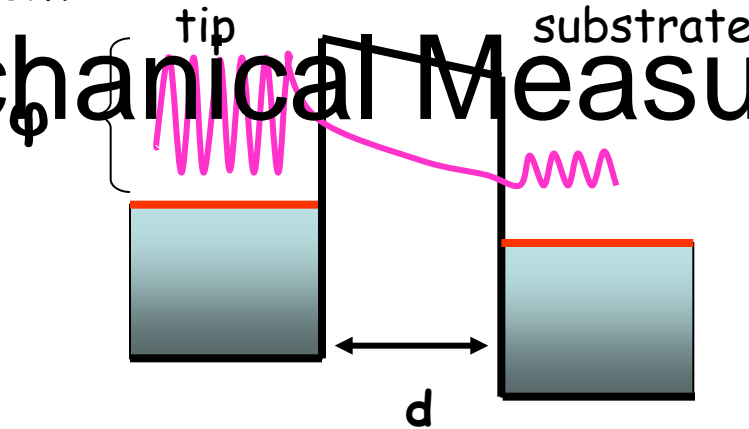
Scanning Electrochemical Microscopy (SECM)

SICM - Scanning Ion Conduction Microscopy

Scanning Spreading Resistance Microscopy (SSRM)

STM - essentially an electrical measurement.

STM and AFM are Electrical and Mechanical Measurements



AFM - essentially a mechanical measurement:

